

Update on Large Sensor Studies

Mechanical Properties, Electrical Properties of Non-irradiated Large Barrel Sensors, inner cut (slim dice), and outer cut (normal dice)

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ATLAS12A Sensors



| | | VPX12518 |
|---|---|----------|
| | | 653 |
| • | another shinment of 20 sensors | 655 |
| | | 656 |
| • | type: ATLAS12A | 657 |
| • | hatch: V/PX12518 | 659 |
| | | 660 |
| • | Wafer list: see table on right | 663 |
| • | SCT ID: 25220901100xxx | 664 |
| | | 665 |
| | where xxx is wafer ID | 668 |
| | | 669 |
| | | 675 |
| • | narrow common P-stop w/ 4E+12 concentration | 679 |
| • | All clim dicing ("Inner Cut") | 687 |
| • | All sinn dicing (inner Cut) | 689 |
| | | 690 |
| | | 691 |
| | | 695 |
| | | 090 |

Metrology measurements summary



Sensor bow determined from z-height points measured by non-contact (optical) measurement microscope. Sensor is freely suspended on a glass plate.

The coordinate system used is pictured on the left: the z-height at the origin (sensor centre) is defined as 0

Sensor net bow is obtianed by subtracting a fitted flat plane from the measurement data points

The table on the right lists the greatest z height difference for the sensor

The plot below, on wafer 655, is typical for the batch





| | 统政 | IINIVERSITY | OF |
|---|----------|-------------|----|
| У | VPX12518 | max z diff | GE |
| | 653 | 56 | |
| | 655 | 34 | |
| | 656 | 30 | |
| | 657 | 45 | |
| | 659 | 54 | |
| | 660 | 38 | |
| | 661 | 29 | |
| | 663 | 32 | |
| | 664 | 49 | |
| | 665 | 34 | |
| | 668 | 31 | |
| | 669 | 45 | |
| | 675 | 28 | |
| | 679 | 27 | |
| | 687 | 40 | |
| | 689 | 36 | |
| | 690 | 38 | |
| | 691 | 41 | |
| | 694 | 50 | |
| | 695 | 40 | |

All sensors are flat within 40µm

NB: VPX12318 batch was flat within 80µm, specification is 200µm

All sensors have convex shape

(centre higher than edges)

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I-V Measurement summary



During measurement, the sensor is sitting in a light-tight box, flushed with N_2 . Due to time constraints, only 2 sensors were measured so far.



W655 initially suffered from early breakdown (at ~800V), this was cured by conditioning, and running the IV once at 10V/1s increments, as is done by HPK, instead of our internally agreed 10V/10s steps.

Both sensors are well within specification

Depletion Measurements summary



Depletion voltage measurement taken directly after IV curve

Sensor is kept in light tight box with N₂ flush.

W653, W655 full depletion reached at 354, 376 V respectively.

Capacitance at 500V bias is 3.147, 3.158 nF, respectively. Measuring the area within the bias ring, and assuming $\epsilon_r(Si)=11.86$, the resulting active depth yields 305 μ m



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